

# MEMS devices for the next generation of sensors

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## Key points and motivations

- Sensors allow electronic systems to gain awareness of the surrounding environment
- The lack of **sensors** with adequate characterists limits the development of innovative electronic systems
- **Sensors** are several generations behind the present stage of electronic HW and SW

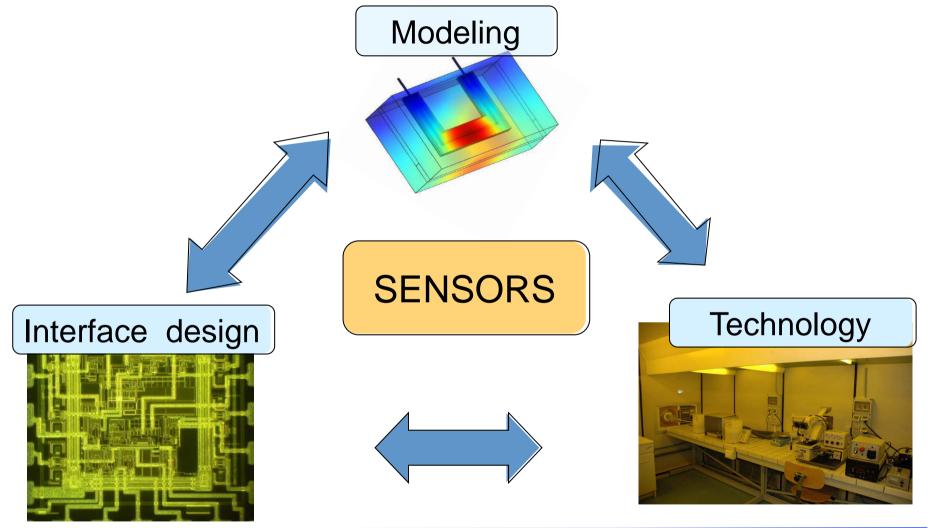


#### New sensors should:

- Expand the range of physical and chemical quantities that can be <u>reliably</u> detected
- Improve miniaturization and reduce power requirements for superior mobile device and WSN compatibility
- Reduce fabrication costs, to facilitate <u>diffusion</u>



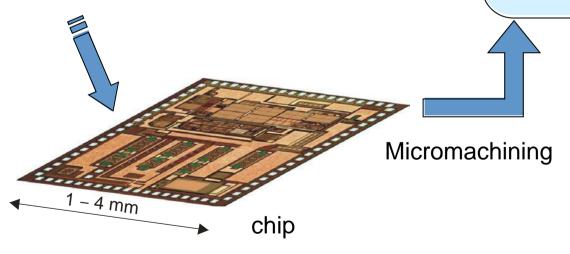
#### Sensor know-how at DII

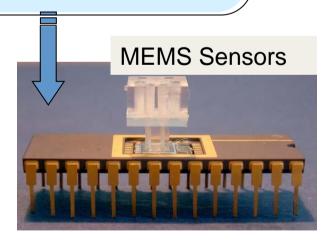


# Technology: the post-processing approach

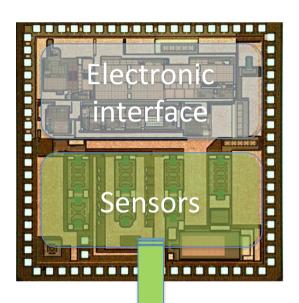
Standard, low cost IC – technology (Silicon Foundry)

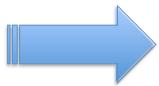
Metal deposition
Photolithography
Anysotropic etching
RIE dry etching
Packaging



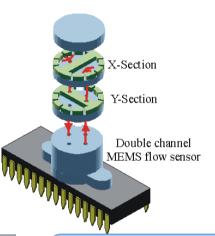


## Example I: smart flow sensor



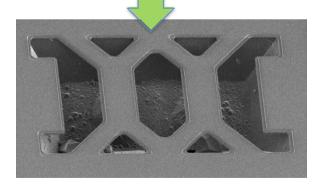


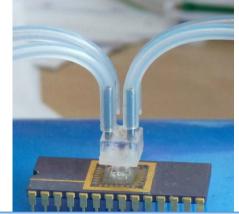
**Products** 



Directional

anemometer



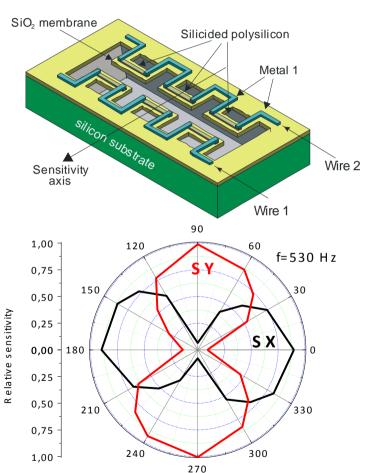


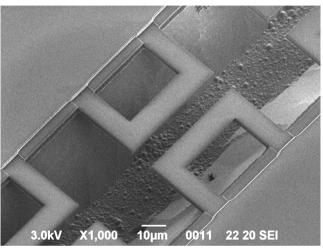
Multi-channel flow sensor



#### Example II: Acoustic particle

#### sensor

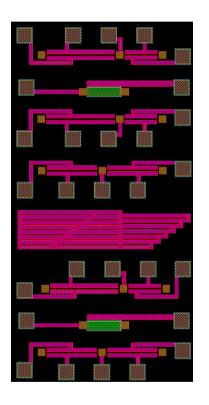




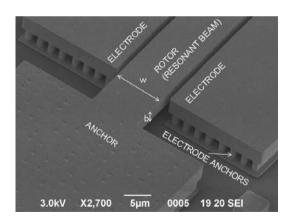
- Detection of the local velocity induced by the sounds on the medium
- Suitable for sound source localization
- ➤ Fully compatible with low-cost CMOS technologies

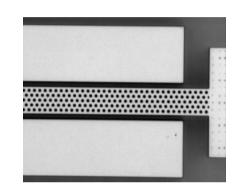


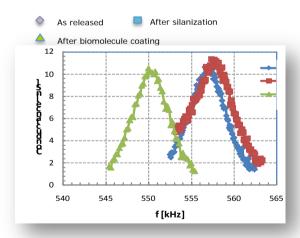
# Example III MEMS (SiGe) Resonant Biosensors



- Application: disposable, very low cost biosensors for POCT applications
- MEMS-over-CMOS technology
- Robust towards surface tension
- Electrical readout
- Sensitivity enhancement (perforations)



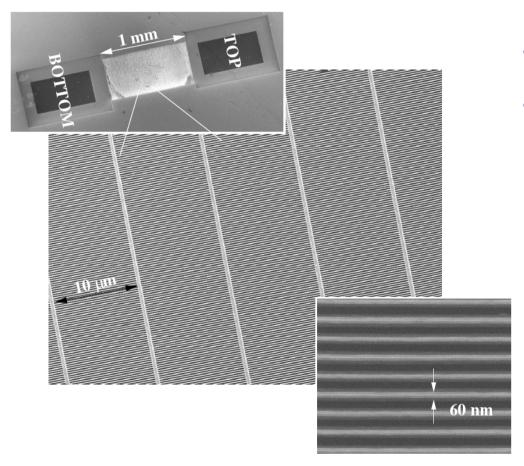




Response to biotin



# **Example IV: NEMS sensors**



- E-BEAM Lithography
- Unique properties of nanostructures with macroscopic capture areas



### MEMS-NEMS group at DII

Analog integrated circuit and thermal sensors:

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The group includes also 3 Ph.D. students and 1 research fellow